The content of the zip file "Dataset" including XRD on a-SiC:Cu films and current-voltage measurements, endurance test on Cu/a-SiC:Cu/Au resistive memories. All the results have been presented in an article “Amorphous SiC resistive memory with embedded Cu nanoparticles", accepted by Microelectronic Engineering.

Rigaku Smartlab X-ray Diffractometer and Keithley 4200SCS Semiconductor Device Analyzer, etc. were used.